

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/553,573  
Applicants: Christian DUSSARRAT, et al.  
Filed Internationally: April 8, 2004  
US National: October 17, 2005  
Title: METHODS FOR PRODUCING SILICON NITRIDE FILMS  
BY VAPOR-PHASE GROWTH  
TC/A.U.: 1762  
Examiner: Elizabeth A. Burkhart  
Docket No.: Serie 6070  
Customer No.: 40582

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of January 5, 2009, please amend the application as follows:

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the Claims** begin on page 3 of this paper.

**Remarks** begin on page 8 of this paper.